

Form PTO-1449 (REV. 8-83)		US Dept. of Commerce PATENT & TRADEMARK OFFICE		ATTY DOCKET NO. 110157.98		APPLICATION NO. 09/779,686	
INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary)				APPLICANT Kenji NISHI			
				FILING DATE February 9, 2001		GROUP 2851	
U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	
AM		3,538,828	11-1970	GENOVESE			
AM		4,747,678	5-1998	SHAFFER et al.			
AM		4,748,478	5-1988	SUWA et al.			
AM		4,749,867	6-1988	MATSUSHITA et al.			
AM		4,822,975	4-1989	TORIGOE			
AM		4,924,257	5-1990	JAIN			
AM		5,004,348	4-1991	MAGOME			
AM		5,187,519	2-1993	TAKABAYASHI et al.			
AM		5,227,839	7-1993	ALLEN			
AM		5,281,996	1-1994	BRUNING et al.			
AM		5,506,684	4-1996	OTA et al.			
AM		5,767,948	6-1998	LOOPSTRA et al.			
AM		5,796,469	8-1998	EBINUMA			
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB CLASS	
AM		JP A 4-196513 (w/abstract)	7-1992	JAPAN			
AM		JP A 63-128713	6-1988	JAPAN			
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)							
AM		Buckley et al., "Step and scan: A systems overview of a new lithography tool", SPIE Vol. 1088 Optical/Laser					
		Microlithography II (1989), p. 424-433.					
EXAMINER Alan Matthews				DATE CONSIDERED 9-18-2002			
Examiner: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							